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Paul R. Tolley, Smart System Technology & Commercialization Center
(United States)
Martin J. Valente, Arizona Optical Systems, LLC (United States)
Kirk J. Warden, LaCroix Optical Company (United States)
Robert Anton Wiederhold, Optimax Systems, Inc. (United States)

Session Chairs

- 1 Grinding and Polishing Processes I
Matthias Pfaff, OptoTech Optikmaschinen GmbH (Germany)

- 2 Grinding and Polishing Processes II
Jessica E. DeGroote Nelson, Optimax Systems, Inc. (United States)
- 3 Grinding and Polishing Processes III
Michael J. Bechtold, OptiPro Systems (United States)
- 4 Optical Fabrication of Freeform Surfaces
Jonathan D. Ellis, University of Rochester (United States)
- 5 Metrology I
Paul Dumas, QED Technologies, Inc. (United States)
- 6 Plenary Session I
Julie L. Bentley, University of Rochester (United States)
- 7 Metrology II
Kate Medicus, Optimax Systems, Inc. (United States)
- 8 Optical Materials, Cleaning, and Coating
Dave Stephenson, JENOPTIK Optical Systems (United States)
- 9 Optical Design
Theodore Tienvieri, Corning Tropel Corporation (United States)
- 10 Optical Engineering
Christopher T. Cotton, ASE Optics (United States)
- 11 Plenary Session II
Julie L. Bentley, University of Rochester (United States)
- 12 Meter Class Optics
Ted Mooney, ITT Exelis (United States)
- 13 Molded Optics
Michael A. Marcus, Lumetrics, Inc. (United States)